



PATENT  
674556-2003.1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s) : CHOY et al.

U.S. Serial No. : 10/024,658

Filing Date : December 17, 2001

Title of Invention : FILM OR COATING DEPOSITION AND  
POWDER FORMATION

Examiner : Frederick John Parker

Art Unit : 1762

745 Fifth Avenue  
New York, NY 10151

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**INFORMATION DISCLOSURE STATEMENT**

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Dear Sir:

The Examiner's attention is respectfully drawn to the documents listed on the accompanying PTO Form 1449. These references were cited in the parent application, USSN 09/091,456. Accordingly, copies of the references have not been enclosed herein as they are available in the file wrapper for USSN 09/091,456.

As these documents present no new issues to patentability, it is respectfully requested that the Examiner considers and makes of record the documents cited herewith and that a copy of Form PTO-1449 be initialed by the Examiner and returned to the undersigned.

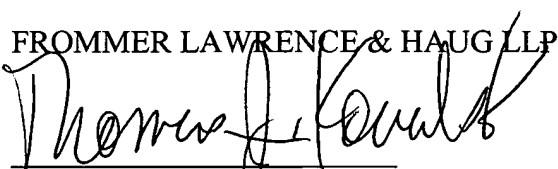
The filing of this Information Disclosure Statement is not an admission that the documents identified herein constitute prior art to the present application.

As this report is being filed with a Request for Continued Examination, it is believed no fee is required. However, the Examiner is authorized to charge any additional fees, or credit any overpayments, to Deposit Account No. 50-0320.

Respectfully submitted,

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<p>Based on Form PTO-1449 (3/90)</p> <p><b>O I P E</b></p> <p><b>JUN 2 3 2005</b></p> <p><b>PATENT TRADEMARK</b></p> <p>LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)</p>			ATTY. DOCKET NO.		SERIAL NO.		
			<b>674556-2003.1</b>		<b>10/024,658</b>		
			APPLICANT				
			<b>CHOY et al.</b>				
			FILING DATE		GROUP		
			<b>December 7, 2001</b>		<b>1762</b>		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
	AL	0 103 505 A1	3/21/84	EUROPE			YES
	AM	0 252 755 A1	1/31/88	EUROPE			NO
	AN	DE 43 32 890 A1	3/24/94	GERMANY			
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AO		Ryu et al., "Fabrication of ZnO thin films using charged liquid cluster beam technique", Applied Physics Letters, vol., 67, no. 22, pp. 3337-3339, 27 November 1995				
	AP		Salata et al., "Fabrication of CdS nanoparticles embedded in a polymer film by gas-aerosol reactive electrostatic deposition technique", Thin Solid Films, vol. 251, no. 1, pp. 1-3, 15 October 1994				
	AQ		Viguerie et al., "Chemical Vapor Deposition at Low Temperatures", Journal of the Electrochemical Society, vol. 122, no. 4, pp. 585-588, 1 April 1975				
	AR		Blandenet et al., "THIN LAYERS DEPOSITED BY THE PYROSOL PROCESS", Thin Solid Films, vol. 77, pp. 81-90, 1981				
EXAMINER				DATE CONSIDERED			
<p>* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							